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Substitute for form 1449A/PTO	Application Number	10/612,793	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Filing Date	July 2, 2003	
	First Named Inventor	Arup Bhattacharyya	
(Use as many sheets as necessary)	Group Art Unit	2826	
	Examiner Name	Thomas Dickey	
Sheet 1 of 1	Attorney Docket No: 1303.111US1		

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